AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claims 1-11 (Canceled)

Claim 12 (Currently Amended): A device for precise machining of a material, comprising:

a pulsed laser system having a beam source[[,]] including

~~wherein the beam source includes a~~ an unamplified cavity-dumped ~~fs~~ femtosecond oscillator; and

a holding device configured to fix the material in a defined position relative to the beam source such that an unamplified output of the cavity-dumped femtosecond oscillator is directed to the material so as to destroy a cohesion of the material using photodisruption.

Claim 13 (Previously Presented): The device as recited in claim 12, wherein the material is an organic material.

Claim 14 (Currently Amended): The device as recited in claim 12, further comprising a beam apparatus for at least one of a beam formation, a beam ~~fuidance~~ guidance, a beam deflection and a beam ~~focussing~~ focusing.

Claim 15 (Previously Presented): The device as recited in claim 14, wherein the beam apparatus is programmable.

Claim 16 (Currently Amended): The device as recited in claim 12, wherein the ~~further comprising a~~ holding device is further configured to ~~one of~~ position ~~and fix~~ the material in the defined position relative to the beam source.

Claim 17 (Currently Amended): The device as recited in claim 12, wherein the cavity-dumped ~~fs~~ femtosecond oscillator is configured to provide laser pulses having a pulse energy of 100 nJ to 100 μJ.

Claim 18 (Previously Presented): The device as recited in claim 17, wherein the pulse energy is 1 μJ.

Claim 19 (Currently Amended): The device as recited in claim 12, wherein the cavity-dumped ~~fs~~ femtosecond oscillator is configured to provide laser pulses with repetition rates from 10 kHz to 10 MHz.

Claim 20 (Currently Amended): The device as recited in claim ~~12~~14, wherein the beam apparatus is configured to apply a working beam of the beam source to the material in a geometrically predeterminable form and in a ~~chronologically~~ temporally predeterminable ~~course~~ pattern.

Claim 21 (Currently Amended): The device as recited in claim 20, wherein the beam apparatus includes a beam deflection device and wherein ~~the~~ a repetition rate of the working beam is changeable during application of the working beam to the material.

Claim 22 (Currently Amended): A method for applying a laser beam to a material, the method comprising:

providing a laser beam having ~~fs~~ femtosecond pulses using a beam source including an unamplified cavity-dumped ~~fs~~ femtosecond oscillator ~~beam source~~;

directing the laser beam without amplification on the material so as to destroy a cohesion of the material in a focus of the laser beam using photodisruption.

Claim 23 (Previously Presented): The method as recited in claim 22, wherein the material is an organic material.

Claim 24 (Currently Amended): The method as recited in claim 22, further comprising guiding the pulsed laser beam onto the material using a deflection apparatus and modifying a repetition rate of the ~~fs~~ femtosecond pulses in relation to a spot pattern produced on the material.

Claim 25 (Currently Amended): The method as recited in claim 23, further comprising performing refractive ~~surgers~~ surgery using the laser beam.

Claim 26 (New): The device as recited in claim 12, wherein the material includes an eye of a human patient.

Claim 27 (New): The device as recited in claim 12, wherein the material includes a cornea of a human patient.

Claim 28 (New): The device as recited in claim 22, wherein the material includes an eye of a human patient.

Claim 29 (New): The device as recited in claim 22, wherein the material includes a cornea of a human patient.